## Supplementary

## **Pressure Sensitive Microparticle Adhesion through**

## **Biomimicry of the Pollen-Stigma Interaction**

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**Figure S1.** SEM images of AFM colloidal-probes of the pollen grains glued to the end of tipless AFM cantilevers. (a) and (d) are the native olive pollen particles; (b) and (e) are the native ragweed pollen particles; (c) and (f) are the native sunflower pollen particles; (g), (h), and (i) the clean particles of olive, ragweed and sunflower pollens respectively. The white scale bar represents 10  $\mu$ m and the black scale bar is 1  $\mu$ m.



Figure S2. FTIR spectra of each cleaned pollen particles.



**Figure S3.** A typical force-distance curves for the interactions of a clean sunflower pollen AFM probe (Psf\_C, spring constant 0.5 N/m) and a flat PDMS substrate at 2.5 nN load forces: the gradient in the contact region was  $0.08 \pm 0.01$  N/m.



**Figure S4.** Force-distributions for the interactions of pollen AFM probes (a: Po\_C; b: Pr\_C; c: Psf\_C) with three PSI-PS substrates under 2.5 nN load force.



**Figure S5.** Adhesion forces for three clean pollen particles of each species (Po\_C, Pr\_C and Psf\_C) interacting with five different substrate surfaces (Si, PS, PS1, PS2 and PSI) under load force 2.5 nN. Error bars are 95% confidence intervals.



**Figure S6.** Force-distance curves for the interactions of sunflower pollen AFM probes (a: Psf\_C; b: Psf\_N) and PSI3 substrate at a series of load forces.



**Figure S7.** Adhesion forces versus load forces for the native pollen particles interacting with five different substrate surfaces. Error bars are 95% confidence intervals.



**Figure S8.** SEM images showing the multiple spines contact to surfaces for freely-settling (a) ragweed and (b) sunflower pollen particles on Si substrates. All scale bars are  $1\mu m$ .

<i>p</i> -value	Po_C	Pr_C	Psf_C
2.5 nN Load Force			
PS-PSI1	0.13	0.32	0.63
PS-PSI2	8.8×10 <sup>-4</sup>	2.1×10 <sup>-4</sup>	2.5×10 <sup>-3</sup>
PS-PSI3	4.4×10 <sup>-7</sup>	1.2×10 <sup>-8</sup>	2.8×10 <sup>-8</sup>
PSI1-PSI2	3.0×10-7	2.2×10 <sup>-10</sup>	3.4×10 <sup>-11</sup>
PSI1-PSI3	1.0×10 <sup>-10</sup>	1.2×10 <sup>-12</sup>	1.5×10 <sup>-13</sup>
PSI2-PSI3	0.19	0.16	0.22
500 nN Load Force			
PS-PSI1	0.45	0.65	0.86
PS-PSI2	3.7×10 <sup>-3</sup>	5.5×10 <sup>-3</sup>	4.3×10 <sup>-4</sup>
PS-PSI3	4.6×10 <sup>-5</sup>	3.3×10 <sup>-6</sup>	5.0×10-7
PSI1-PSI2	2.3×10 <sup>-7</sup>	3.4×10 <sup>-8</sup>	2.4×10 <sup>-11</sup>
PSI1-PSI3	2.1×10 <sup>-11</sup>	7.2×10 <sup>-10</sup>	2.8×10-13
PSI2-PSI3	0.12	0.08	0.09

Table S1. Possibility (*p*-value) of no significant difference of adhesion forces between each substrates under 2.5 nN and 500 nN load forces.